

03500.015381

PATENT APPLICATION



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
	:	Examiner: Bret P. Chen
TAKAHARU KONDO, ET AL.)	
	:	Group Art Unit: 1762
Application No.: 09/865,549)	
	:	
Filed: May 29, 2001)	
	:	
For: METHOD OF FORMING)	
SILICON-BASED THIN FILM,	:	
SILICON-BASED THIN FILM)	
AND PHOTOVOLTAIC	:	
ELEMENT)	April 10, 2003

Commissioner for Patents
Washington, D.C. 20231

AMENDMENT

Sir:

a) Introductory Comments:

This Amendment is filed in accordance with the OG.Notice -1267 Off. Gaz.
Pat.Office 106 of February 25, 2003 - in which 37 C.F.R. §1.121(a)-(d) is waived for amendments
to the application where the Amendment complies with the Revised Amendment Format of the OG
Notice.

In response to the outstanding restriction requirement dated March 12, 2003, kindly
amend the subject application as follows: